

WHAT IS CLAIMED IS:

1. A conveyor device for a flexible substrate, said conveyor device comprising:
 - a conveying means for continuously conveying a flexible substrate from one end to the other end;
 - 5 a plurality of cylindrical rollers being provided between the one end and the other end along an arc with a radius R;
 - wherein center axes of the plurality of cylindrical rollers run parallel to each other; and
 - 10 a mechanism for conveying the flexible substrate while the substrate is in contact with each of the plurality of cylindrical rollers.
2. A device according to claim 1,
 - wherein the radius R of the arc is in a range of 0.5 to 10 m.
3. A film formation apparatus for a flexible substrate, said film formation apparatus comprising:
 - 15 a conveying means for continuously conveying a flexible substrate from one end to the other end;
 - a plurality of cylindrical rollers being provided between the one end and the other end along an arc with a radius R;
 - wherein center axes of the plurality of cylindrical rollers run parallel to each other; and
 - 20 a mechanism for conveying the flexible substrate while the substrate is in contact with each of the plurality of cylindrical rollers.
4. An apparatus according to claim 3,

wherein the radius R of the arc is in a range of 0.5 to 10 m.

5. An apparatus according to claim 3 further comprising:

a vacuum chamber;

an introducing means for introducing a gas into the vacuum chamber;

5 a gas evacuation means; and

an energy supplying means for supplying an energy to make a plasma from the
gas.

6. An apparatus according to claim 3,

wherein the film formation apparatus is a plasma CVD apparatus.

10 7. An apparatus according to claim 5,

wherein the energy is an electromagnetic wave.